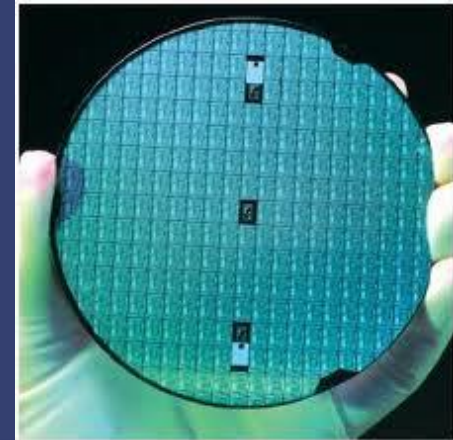
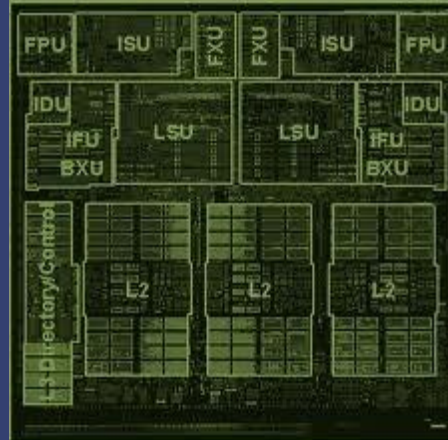
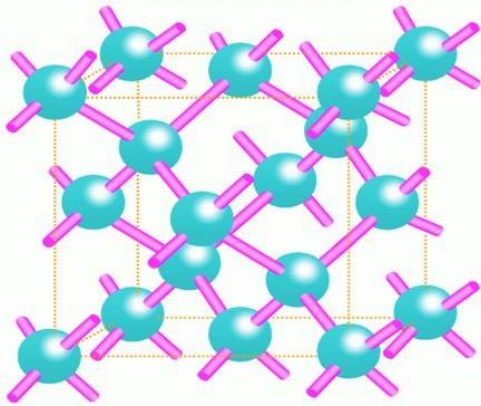


Structure of silicon crystal



# ECE 225

## Lecture 12

### *Nanoscale Power and Thermal Management: Self-consistent Thermal Profile Estimation Design-Specific Metric Optimization IC Cooling Analysis*

*Prof. Kaustav Banerjee  
Electrical and Computer Engineering  
University of California, Santa Barbara*

---

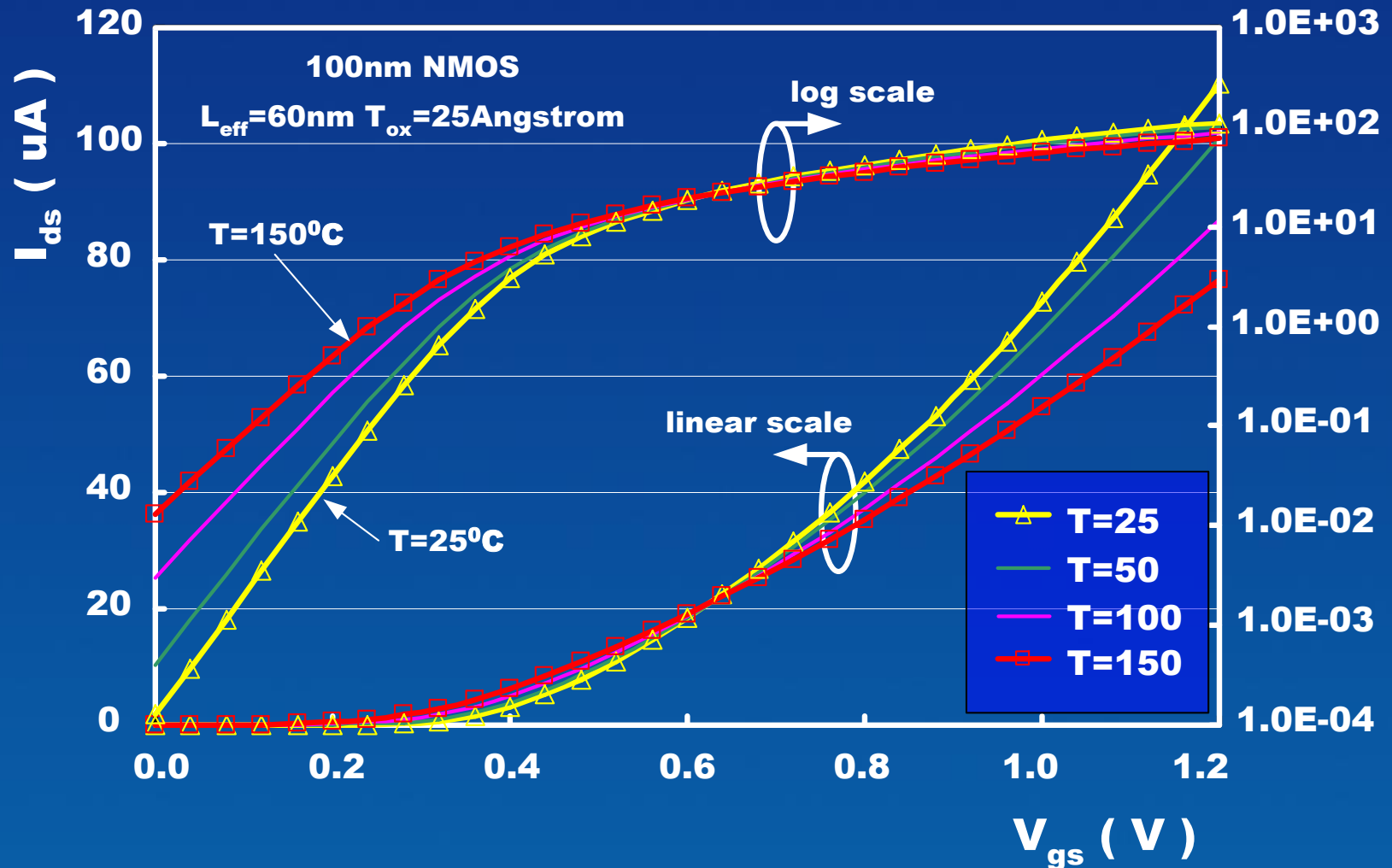
# Self-Consistent Temperature Profile Estimation

S-C. Lin, G. Chrysler, R. Mahajan, V. De and K. Banerjee, “A Self-Consistent Substrate Thermal Profile Estimation Technique for Nanoscale ICs—Part I: Electrothermal Couplings and Full-Chip Package Thermal Model,” TED Vol. 54, No. 12, pp. 3342-3350, 2007.

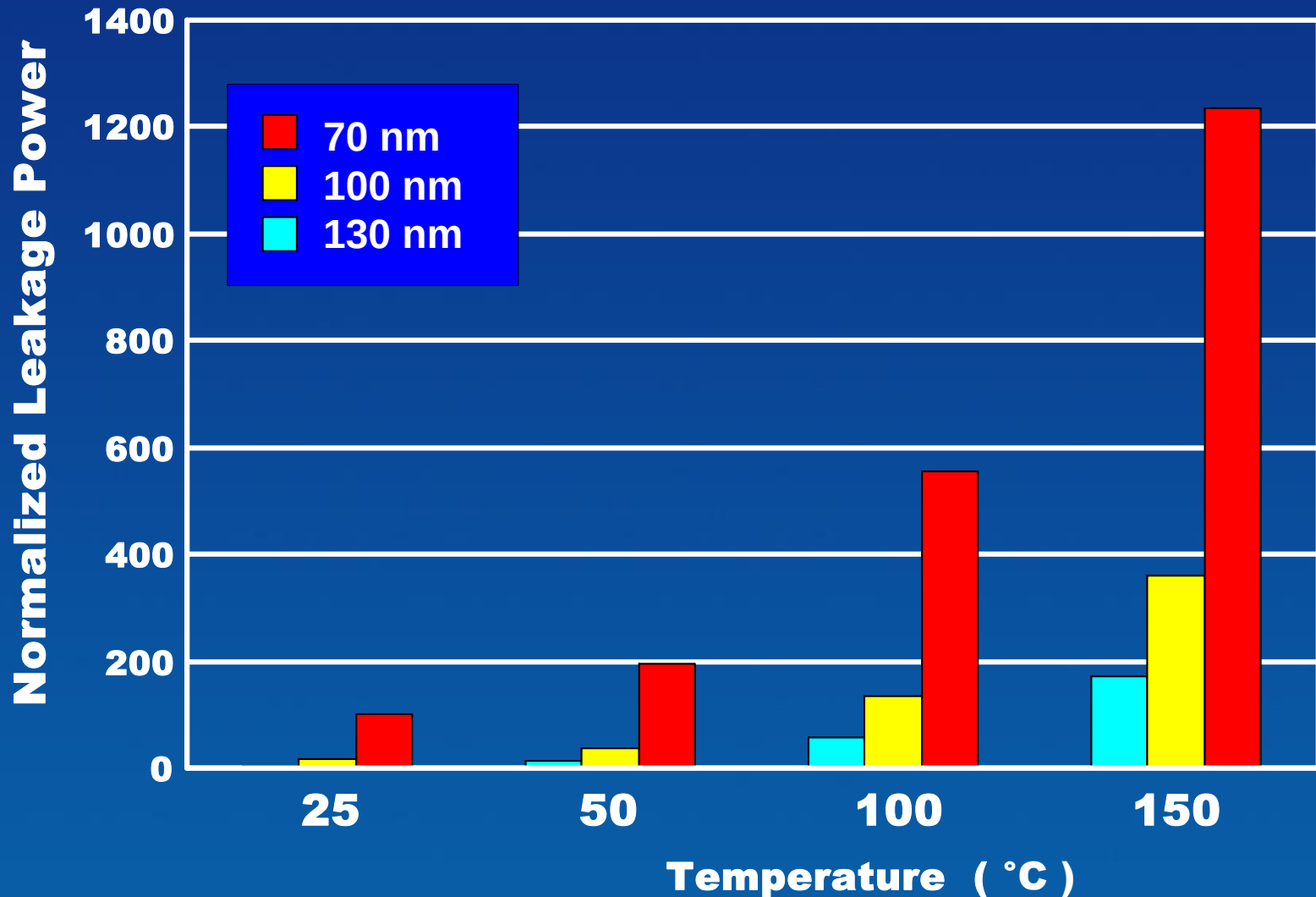
S-C. Lin, G. Chrysler, R. Mahajan, V. De and K. Banerjee, “A Self-Consistent Substrate Thermal Profile Estimation Technique for Nanoscale Part II: Implementation and Implications for Power Estimation and Thermal Management,” TED Vol. 54, No. 12, pp. 3351-3360, 2007.



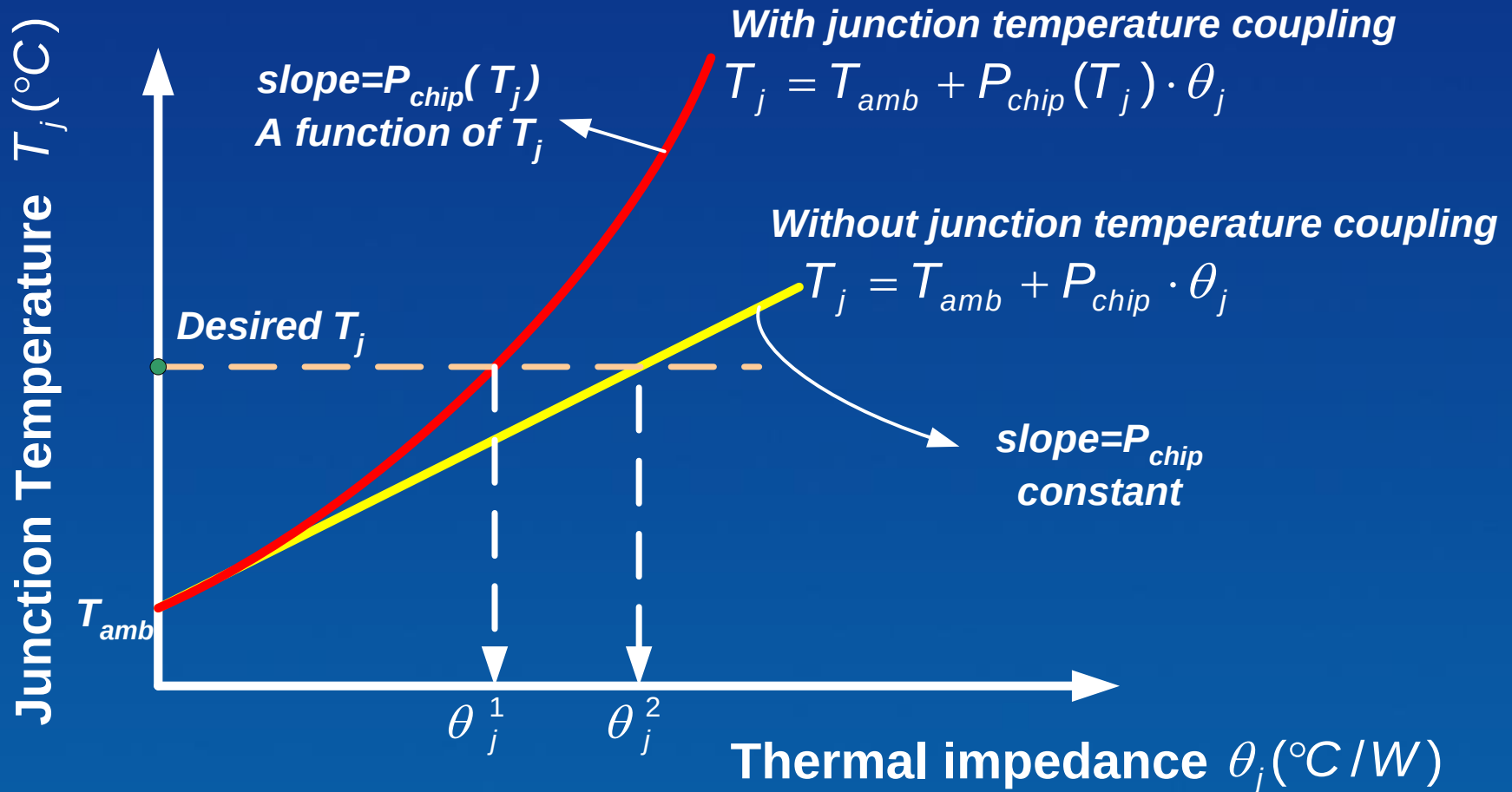
# Subthreshold Leakage Current



# Leakage Power Scaling



# $P_{chip}$ dependency



# Coupling Models

$$F = f_1(V_{dd}, V_t, T_j, L_{nom}, \Delta V_t)$$

$$P_{wa} = \alpha C V_{dd}^2 F$$

$$P_{wsl} = f_2(V_{dd}, V_t, T_j, L_{nom}, \Delta V_t)$$

$$P_{wgl} = f_3(V_{dd}, V_t, t_{ox})$$

$$R = f_4(V_{dd}, V_t, T_j, L_{nom}, \Delta V_t, t_{ox})$$

$$\Delta V_t = f_5(L_{nom}, t_{ox}, X_j, V_{dd}, \Delta L)$$

$$T_j = T_{amb} + \theta_j (P_{wa} + P_{wsl} + P_{wgl})$$

$F \rightarrow$  Frequency

$P_{wa} \rightarrow$  Active Power

$P_{wsl} \rightarrow$  Subthreshold Leakage

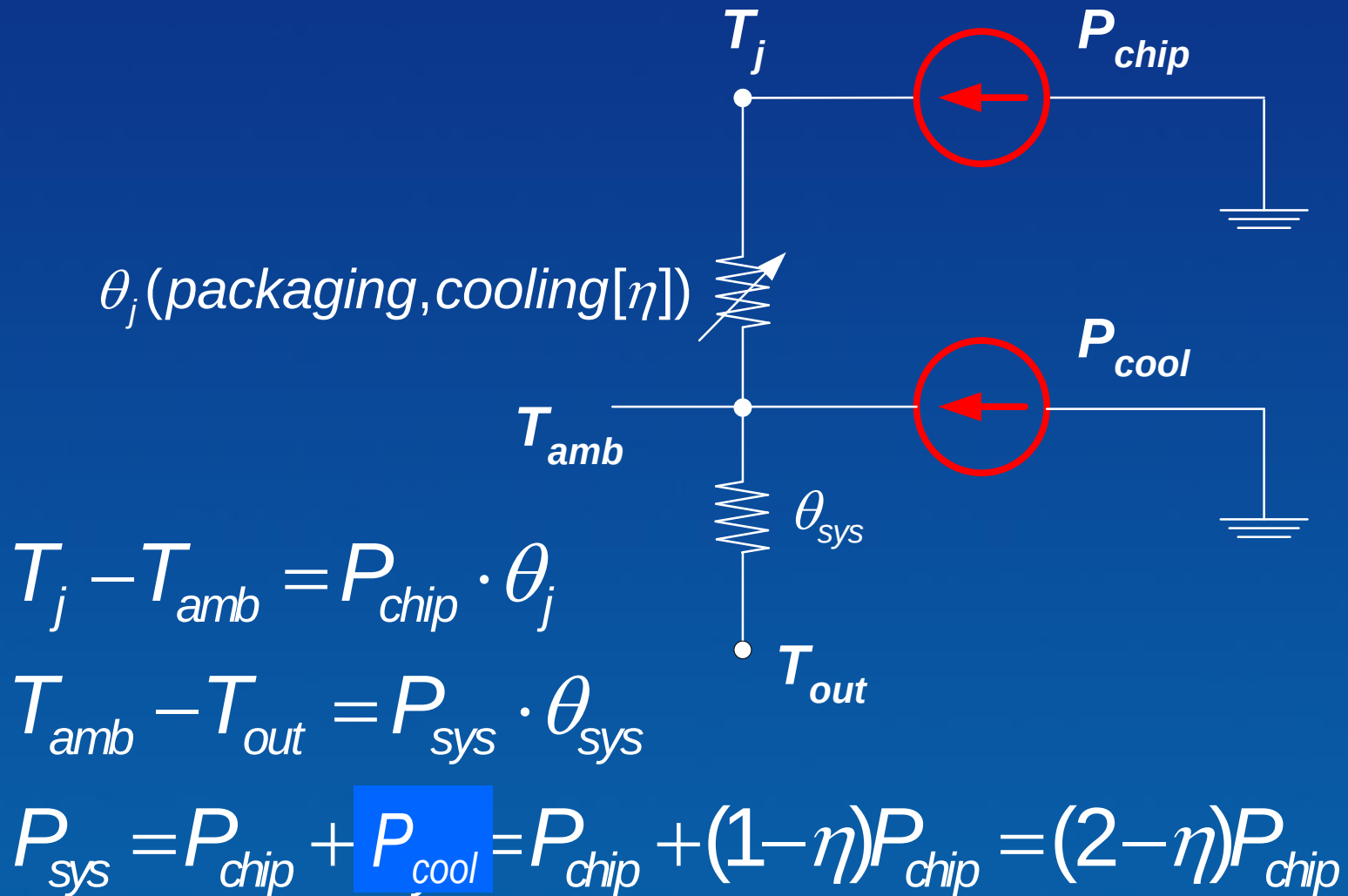
$P_{wgl} \rightarrow$  Gate Leakage

$R \rightarrow$  Reliability Factor

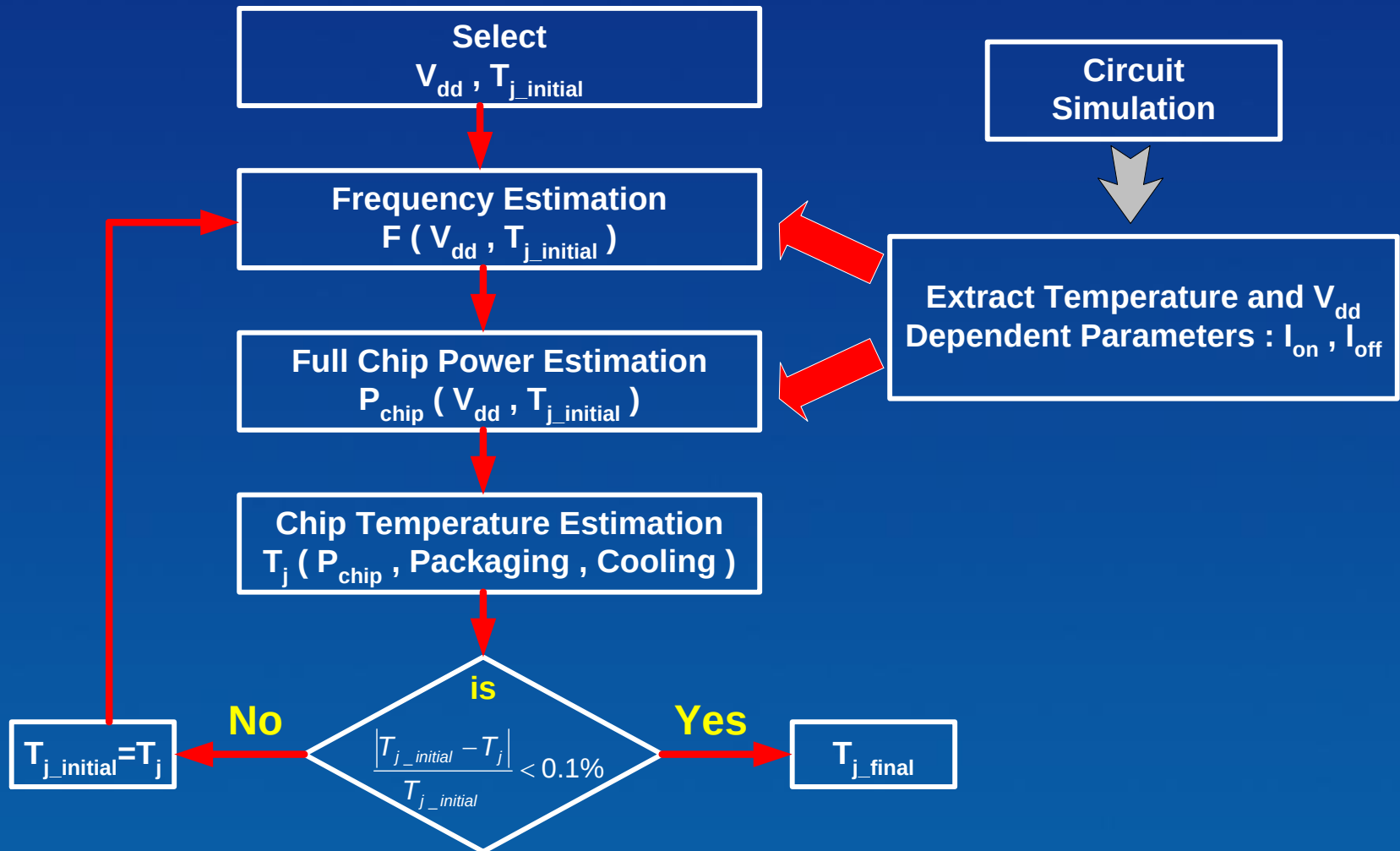
$\Delta V_t \rightarrow$  Threshold Voltage Variation



# Equivalent Thermal Circuit

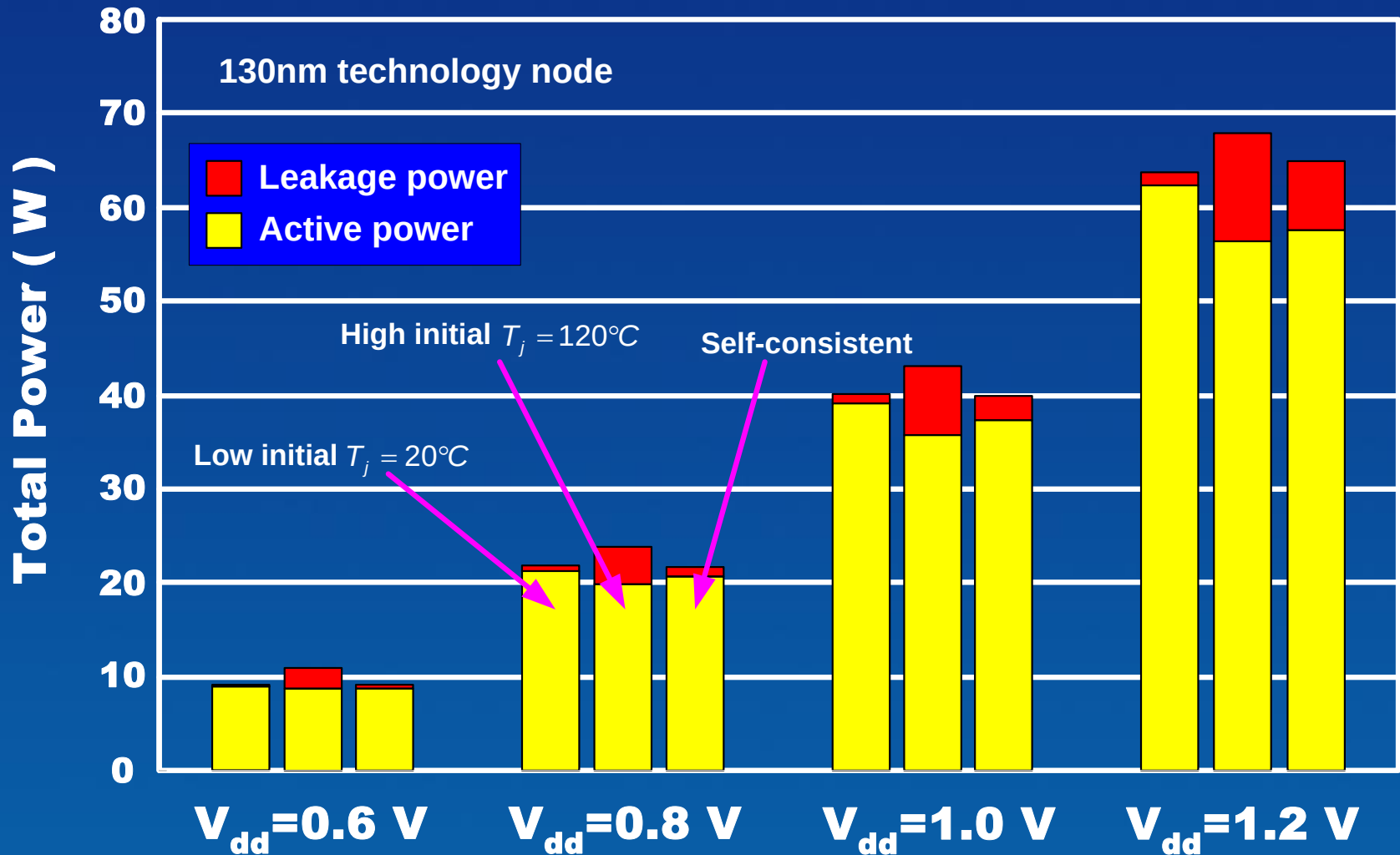


# Overview

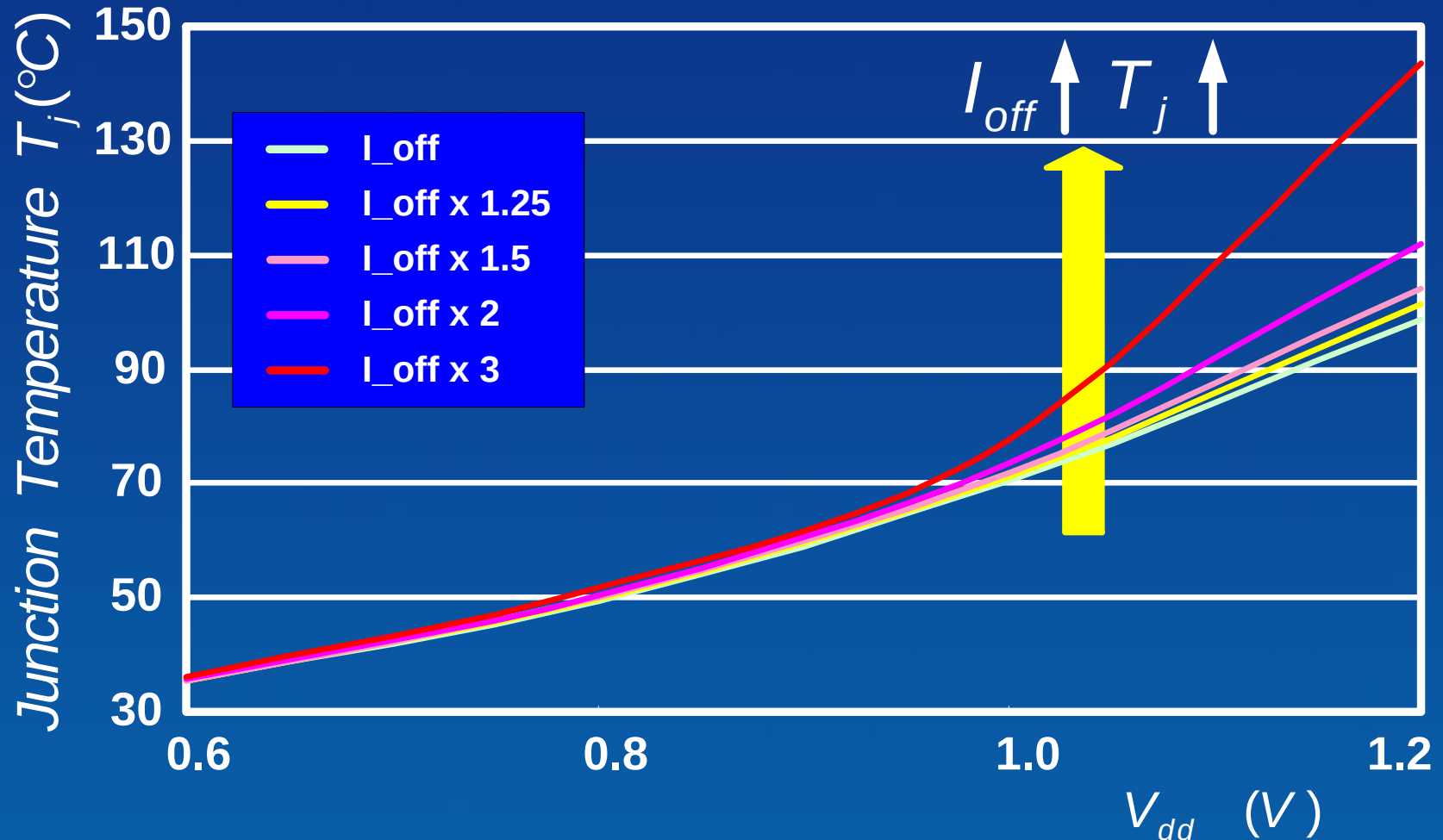




# Total Power Dissipation

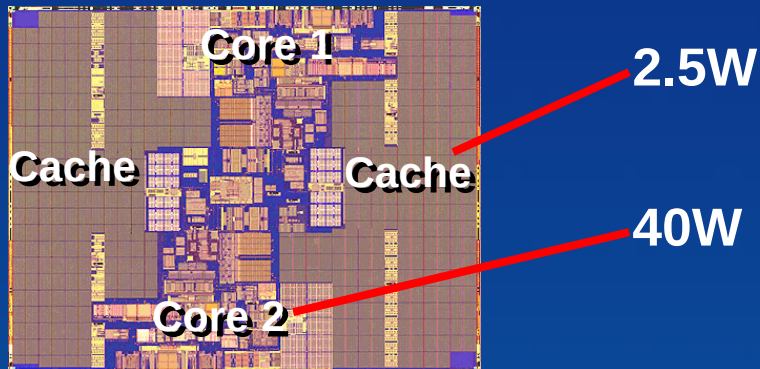


# Self-Consistent Junction Temperature

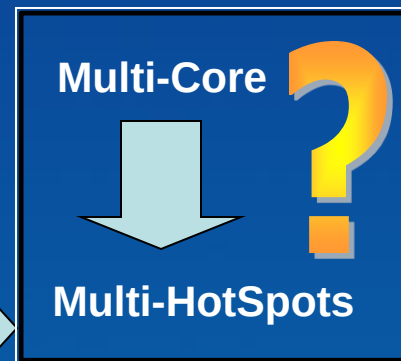
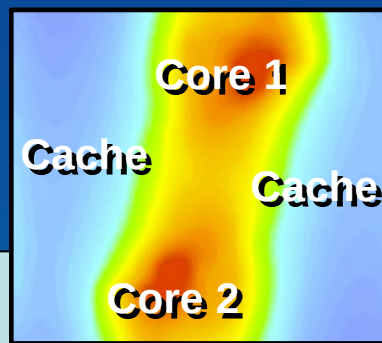
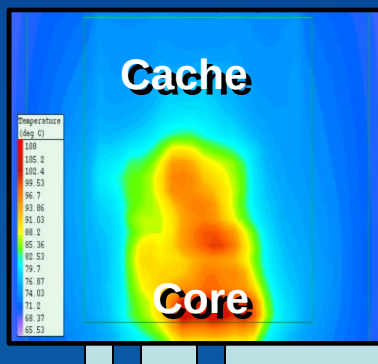
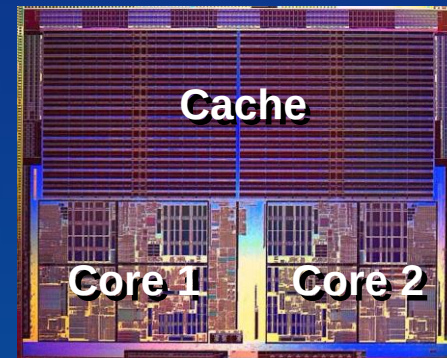


# Non-Uniform Power Density

Intel's first dual-core  
Itanium-Montecito 90nm



AMD's first dual-core  
Athlon 64 X2 90nm SOI



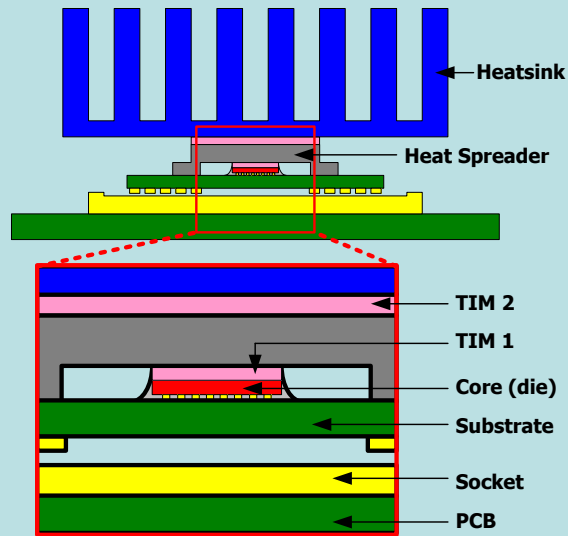
S. Borkar, DAC 2003 C. Poirier, ISSCC 2005

Non-uniform power density generates on-chip temperature gradient

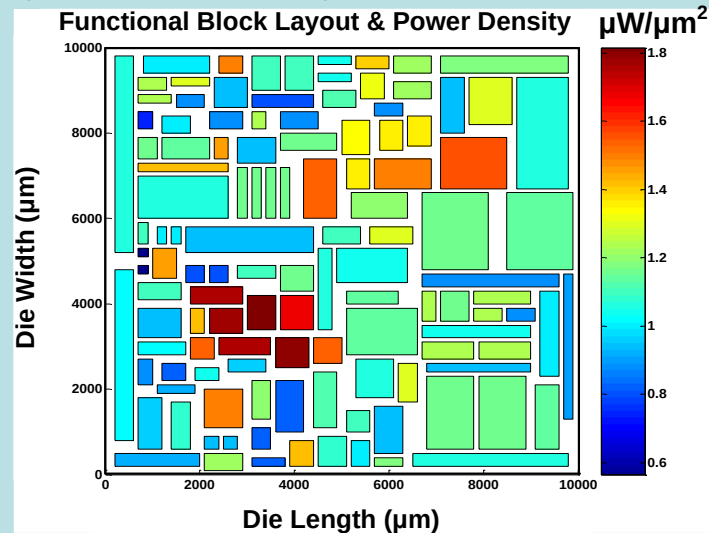


# Methodology Overview

## Packaging / Cooling Model



## Layout Geometry & Power Dissipation



$$\frac{\partial T}{\partial n_i} = \frac{h}{K} [T - T_{amb}]$$

Boundary Condition

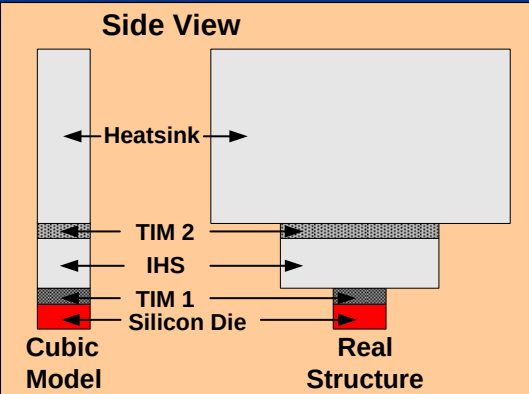
$$\frac{\partial T}{\partial t} = \left( \frac{K}{\rho C_p} \right) \left( \frac{\partial^2 T}{\partial x^2} + \frac{\partial^2 T}{\partial y^2} + \frac{\partial^2 T}{\partial z^2} \right) + \frac{p}{\rho C_p}$$

Parabolic Heat  
Partial Differential Equations

Electrothermal  
Couplings

3-D Electrothermally-Aware  
Spatial Temperature Estimation

# Numerical Approach



$$\frac{\partial T}{\partial t} = \frac{k}{\rho C_p} \left( \frac{\partial^2 T}{\partial x^2} + \frac{\partial^2 T}{\partial y^2} + \frac{\partial^2 T}{\partial z^2} \right) + \frac{p}{\rho C_p}$$

$$\beta_x = \frac{k \Delta t}{2 \Delta x^2 \rho C_p}$$

Crank-Nicholson  
Implicit Method

$$\frac{M_x T}{\Delta x^2} = \frac{T_{i+1,j,k} - 2T_{i,j,k} + T_{i-1,j,k}}{\Delta x^2}$$

$$\frac{\partial^2 T}{\partial x^2} = \frac{1}{2} \left( \frac{M_x T^{n+1}}{\Delta x^2} + \frac{M_x T^n}{\Delta x^2} \right)$$

$$\frac{T^{n+1} - T^n}{\Delta t} = \left( \frac{k}{\rho C_p} \right) \left[ \left( \frac{M_x}{2 \Delta x^2} + \frac{M_y}{2 \Delta y^2} + \frac{M_z}{2 \Delta z^2} \right) (T^{n+1} + T^n) \right] + \frac{p}{\rho C_p}$$

$$(1 - \beta_x M_x - \beta_y M_y - \beta_z M_z)(T^{n+1} - T^n) = 2(\beta_x M_x + \beta_y M_y + \beta_z M_z)T^n + \frac{\Delta t}{\rho C_p} p$$

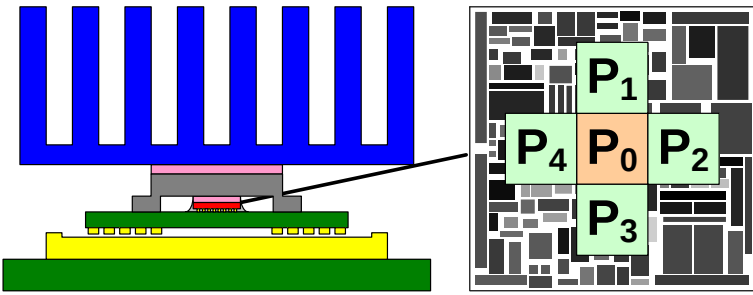
$$(1 - \beta_x M_x)(1 - \beta_y M_y)(1 - \beta_z M_z)(T^{n+1} - T^n) = 2(\beta_x M_x + \beta_y M_y + \beta_z M_z)T^n + \frac{\Delta t}{\rho C_p} p$$

**Linear Equations:**  $(1 - \beta_x M_x)U_{x,y,z} = V_{x,y,z}$

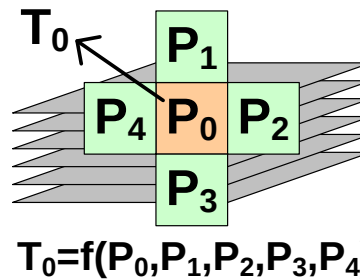


# Self-Consistent Evaluation

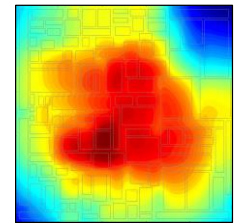
Package & Power Distribution



Traditional Evaluation

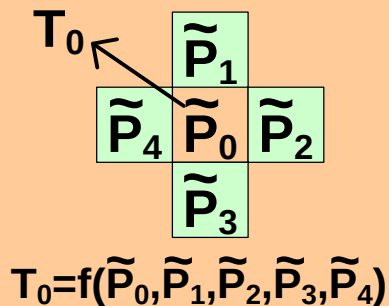


Steady-State Temperature Profile

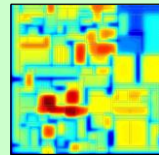


Update temperature dependent power

Self-Consistent Evaluation

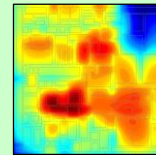


From  $P(t_0)$   
Solve  $T(t_0 + \Delta t)$



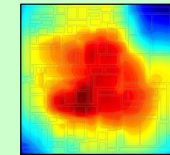
$P(t_0) \rightarrow P(t_0 + \Delta t)$

From  $P(t_0 + \Delta t)$   
Solve  $T(t_0 + 2\Delta t)$



$P(t_0 + \Delta t) \rightarrow P(t_0 + 2\Delta t)$

Steady-State Temperature profile



Steady-State P



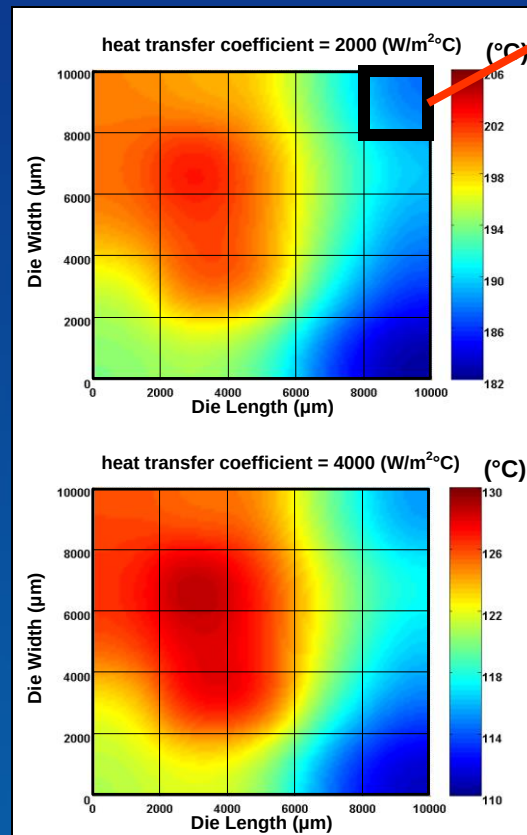
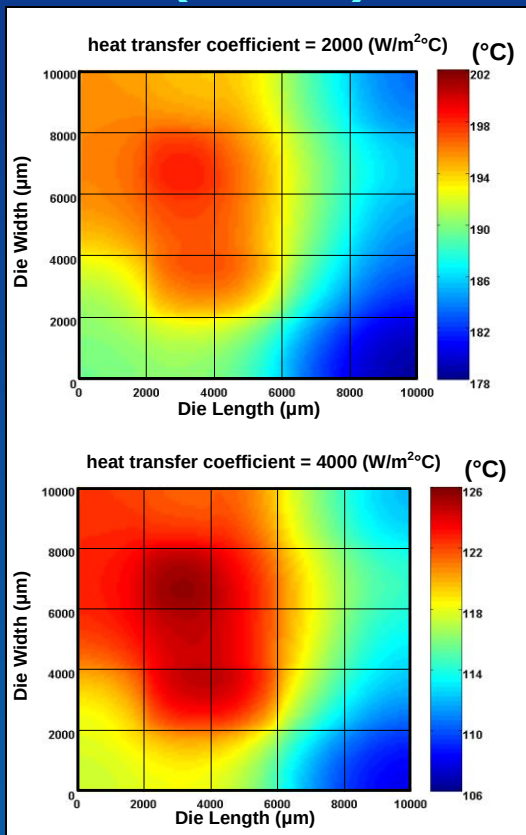
# Methodology Verification

For a case with negligible leakage

Commercial Tool  
(IcePak)

Proposed Method

Equally select 400 data points  
from identical locations for  
comparison (total = 10000 pts)

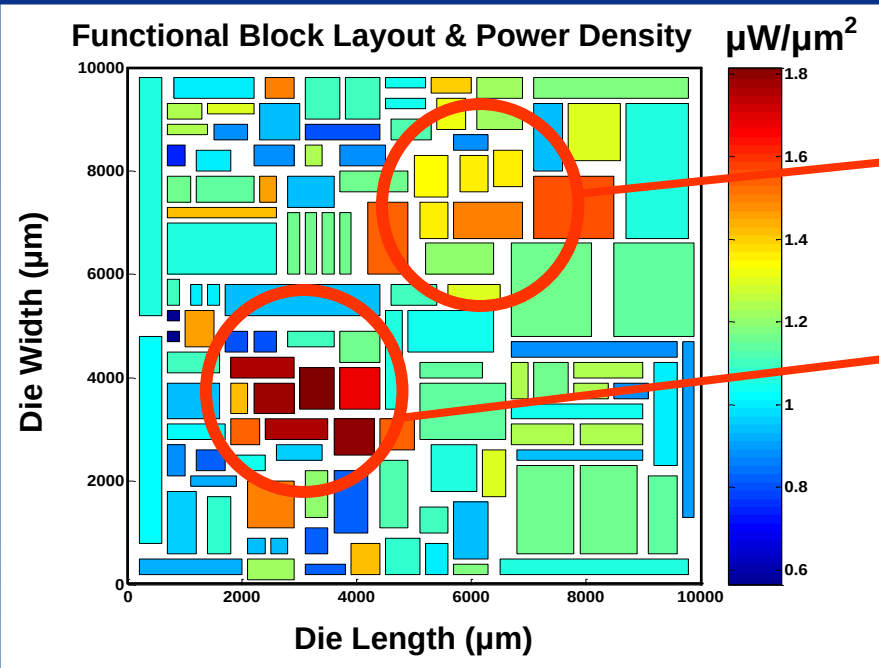


| Coefficient | Max. Deviation |
|-------------|----------------|
| $h=1000$    | 2.13 %         |
| $h=2000$    | 2.48%          |
| $h=3000$    | 3.26 %         |
| $h=4000$    | 3.28 %         |
| $h=5000$    | 3.06 %         |

Proposed method is validated against an industrial-quality software.



# Implementation & Setup



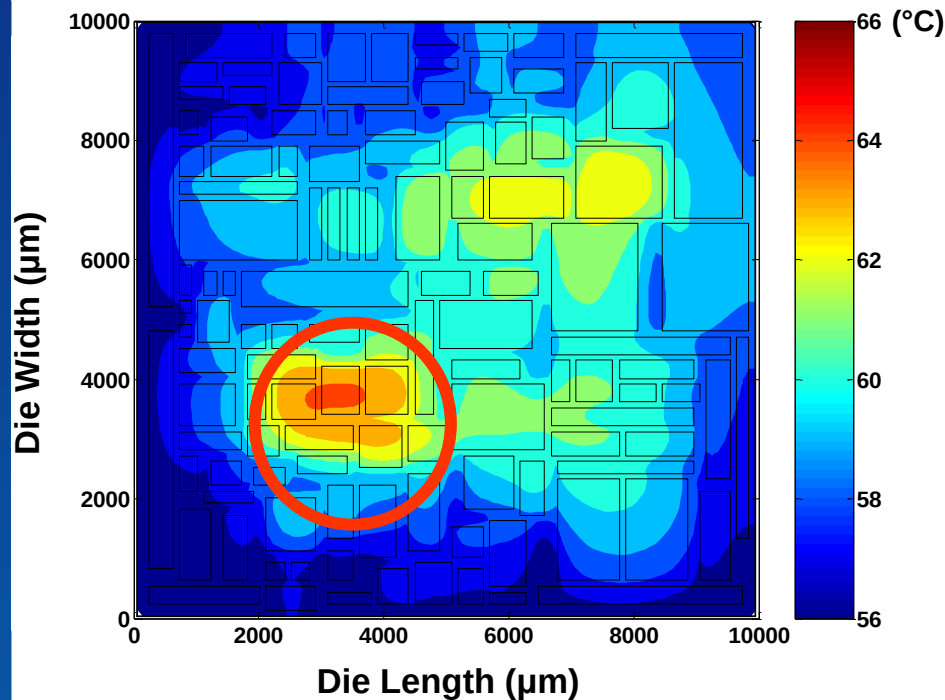
| Layer    | Area ( $\text{mm}^2$ ) | Thickness (mm) | Specific Heat ( $\text{J}/\text{kg}^\circ\text{C}$ ) | Density ( $\text{kg}/\text{m}^3$ ) | K ( $\text{W}/\text{m}^\circ\text{C}$ ) |
|----------|------------------------|----------------|------------------------------------------------------|------------------------------------|-----------------------------------------|
| Die      | 10 X 10                | 0.8            | 712                                                  | 2330                               | 120                                     |
| TIM 1    | 10 X 10                | 0.2            | 230                                                  | 7310                               | 30                                      |
| IHS      | 30 X 30                | 1.8            | 385                                                  | 8930                               | 390                                     |
| TIM 2    | 30 X 30                | 0.2            | 2890                                                 | 900                                | 6.4                                     |
| Heatsink | 60 X 60                | 6.4            | 385                                                  | 8930                               | 360                                     |



# Impact of Considering ET-couplings

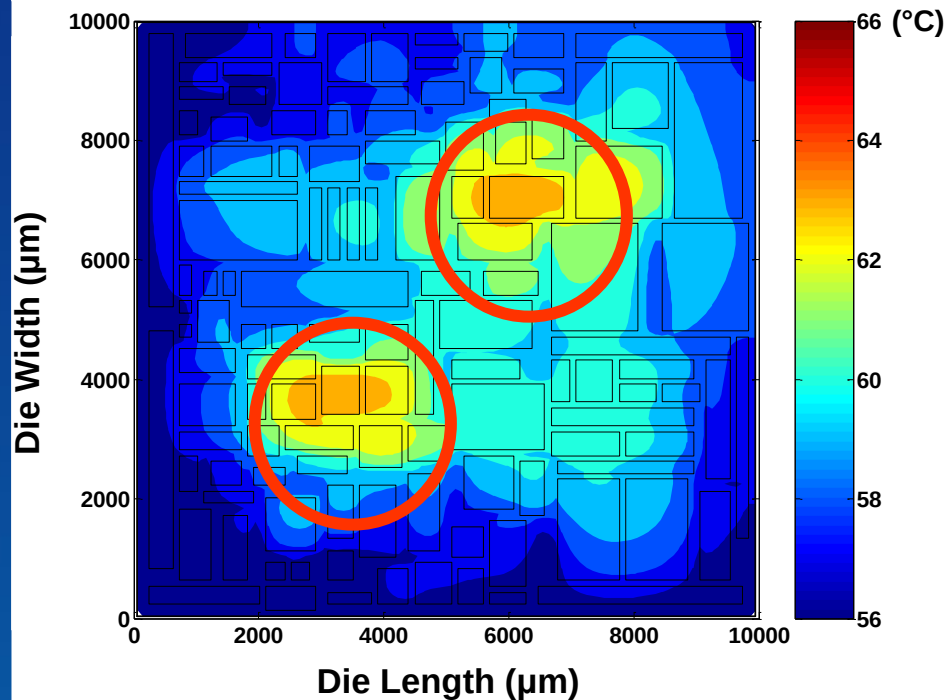
## Without ET-Couplings

Traditional Evaluation + Realistic Package Thermal Model



## With ET-Couplings

Electrothermally-Aware + Realistic Package Thermal Model



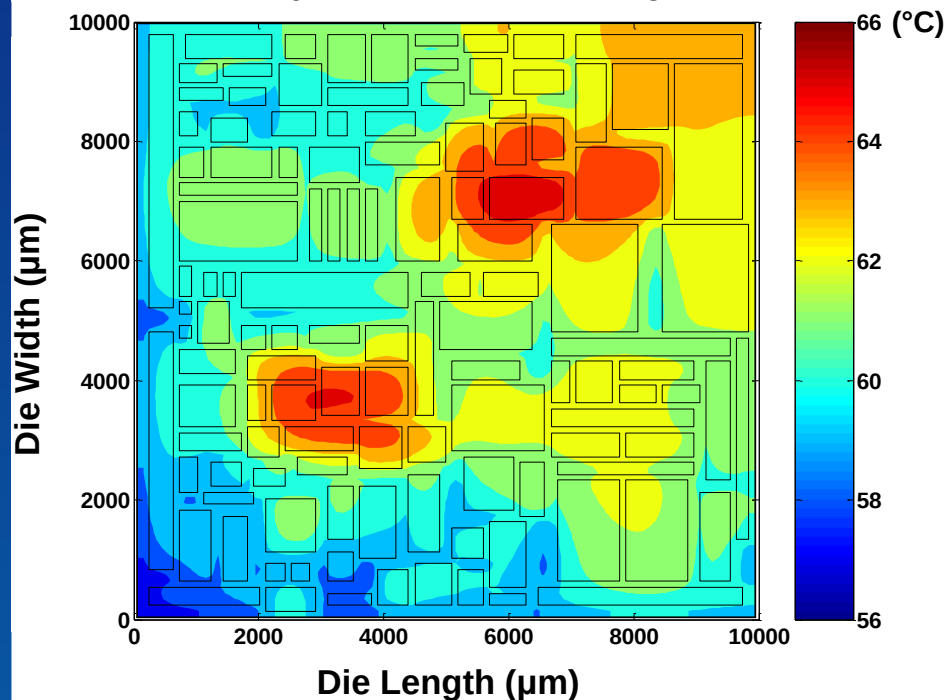
- ❖ Traditional evaluation neglects electrothermal couplings
- ❖ Considering electrothermal couplings leads to an additional hot-spot at the highest leakage power region



# Impact of Package Models

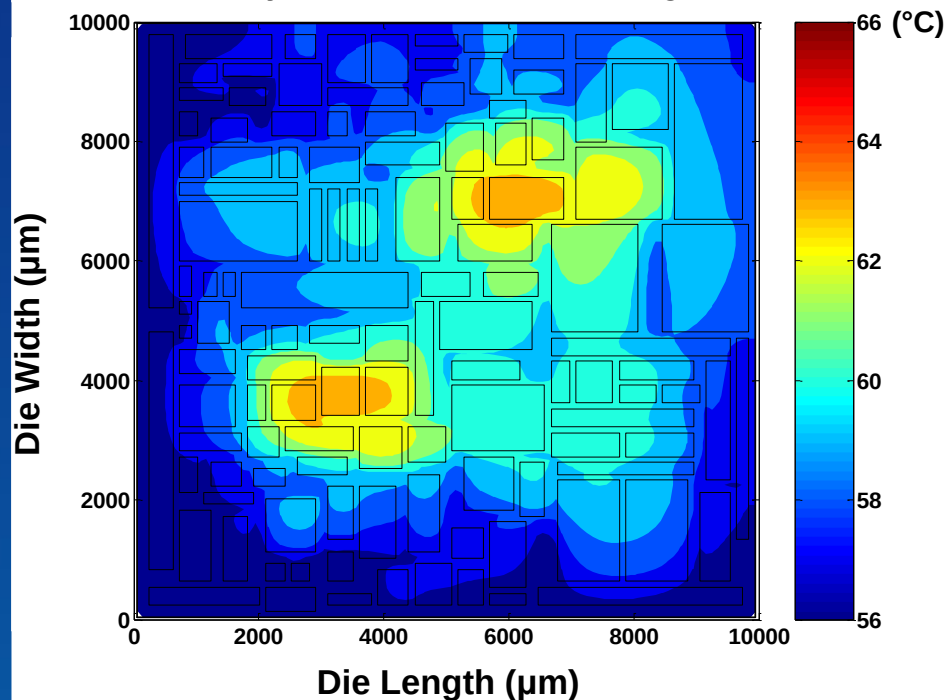
## Cubic Package Thermal Model

Electrothermally-Aware + Cubic Package thermal Model



## Realistic Package Thermal Model

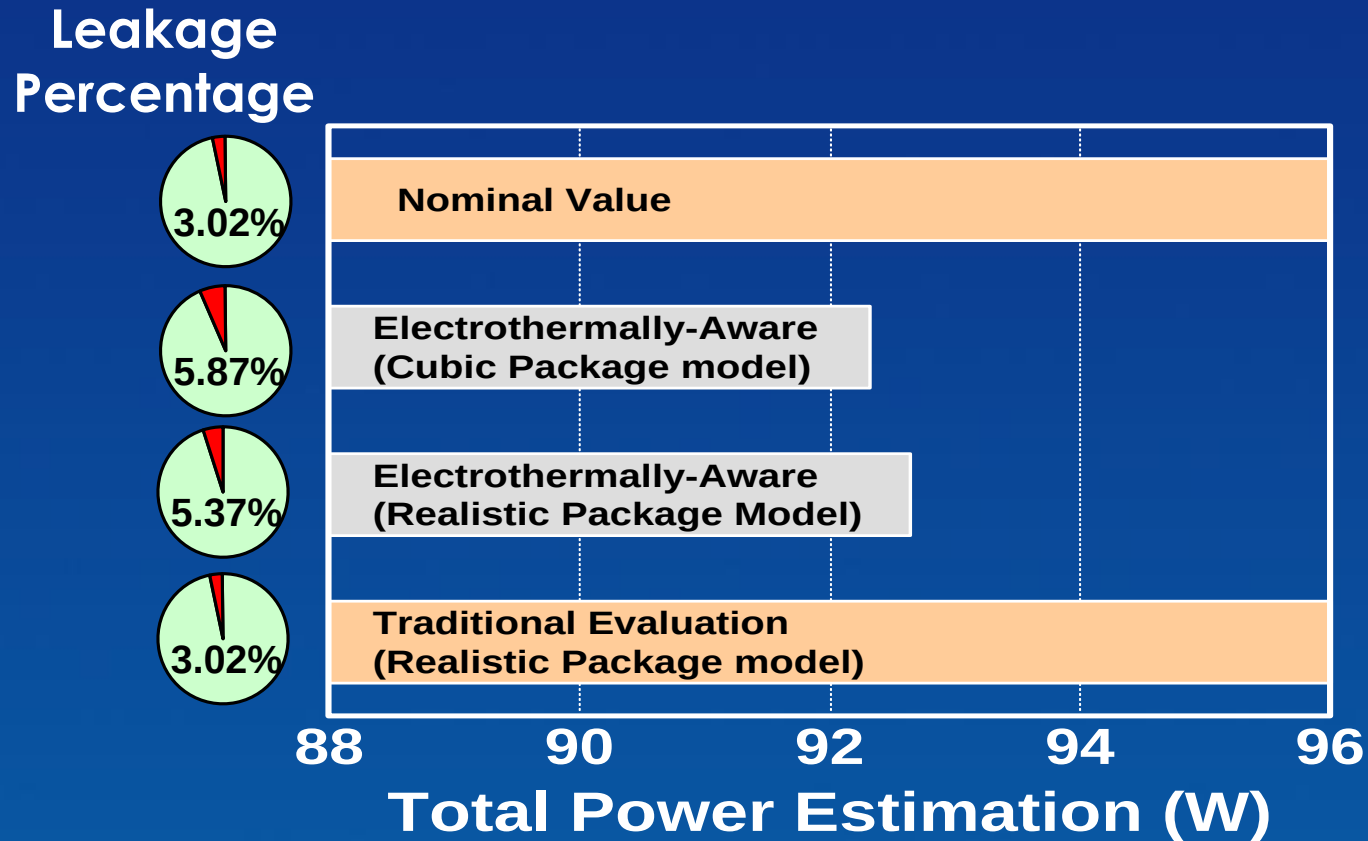
Electrothermally-Aware + Realistic Package Thermal Model



- ❖ Simple cubic package thermal model ignores physical dimensions of different packaging layers and neglects lateral heat spreading
- ❖ Simple cubic model over-estimates the temperature profile



# Implications for Power Estimation



- ❖ Power is not consistent with temperature in traditional evaluation
- ❖ Considering cubic package model overestimates leakage power



# Design-Specific Metric Optimization

S-C. Lin and K. Banerjee, "A Design-Specific and Thermally-Aware Methodology for Trading-Off Power and Performance in Leakage-Dominant CMOS Technologies," TVLSI Vol. 16, No. 11, pp. 1488-1498, 2008.

## Target:

**Find a minimal value of Energy-Delay-Product for operation.**

M. Horowitz, 1997

## Delay

**Delay of various gates in the critical path remains proportional to the delay of an equivalent inverter.**

**Can be evaluated by Alpha-Power model**

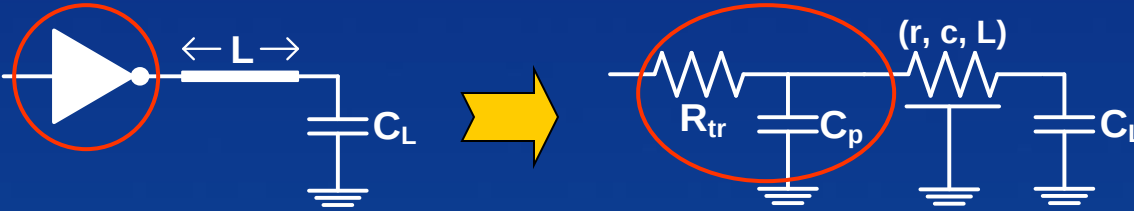
T. Sakurai and A. R. Newton, 1990

## Energy

**Can be calculated by total power dissipation**



# Incorporate Interconnect Effects in EDP Optimization



$$\tau = R_{tr}(C_p + C_L + cL) + rLC_L + \left(\frac{1}{2}\right)rcL^2$$

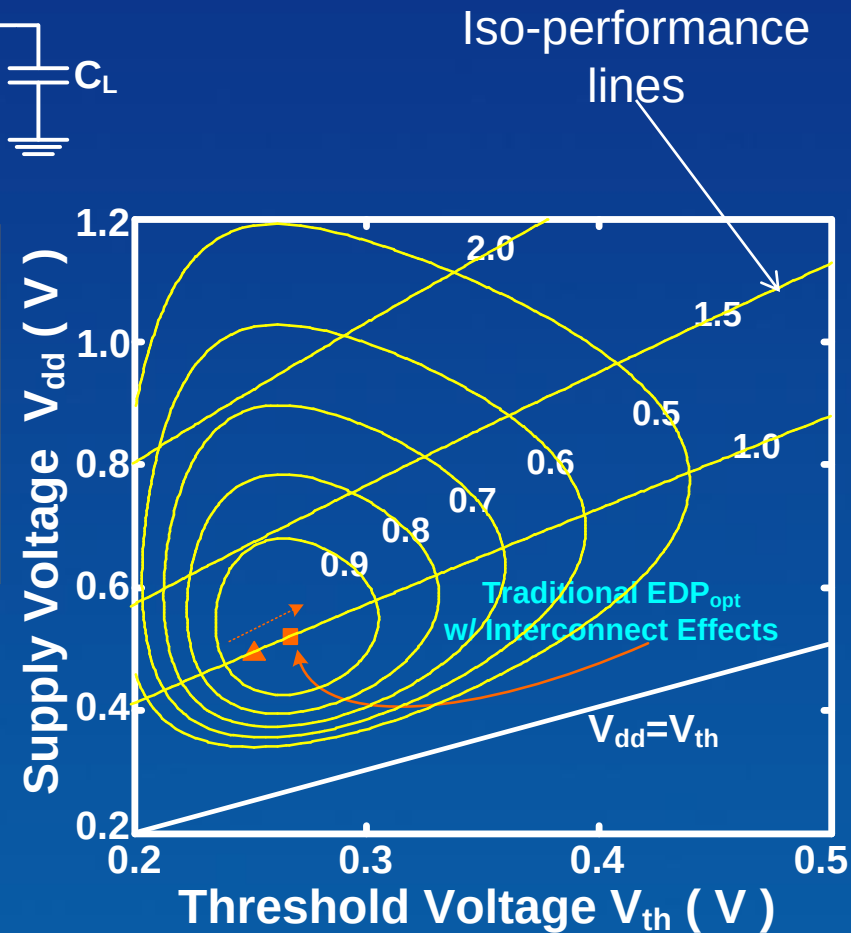
$$T_g \cong 0.69R_{tr}(C_p + C_L + cL) + 0.69rLC_L + 0.38rcL^2$$

$$T_g \cong \frac{KV_{dd}}{(V_{dd} - V_{th})^\alpha} \left[ 1 + \frac{cL}{C_p + C_L} \right] + 0.69rLC_L + 0.38rcL^2$$

$$P_{dynamic} = aC_{eff}V_{dd}^2F$$

$$P_{static} = I_s e^{-V_{th}/\gamma V_o} (1 - e^{-V_{ds}/\gamma V_o}) W_{eff} V_{dd}$$

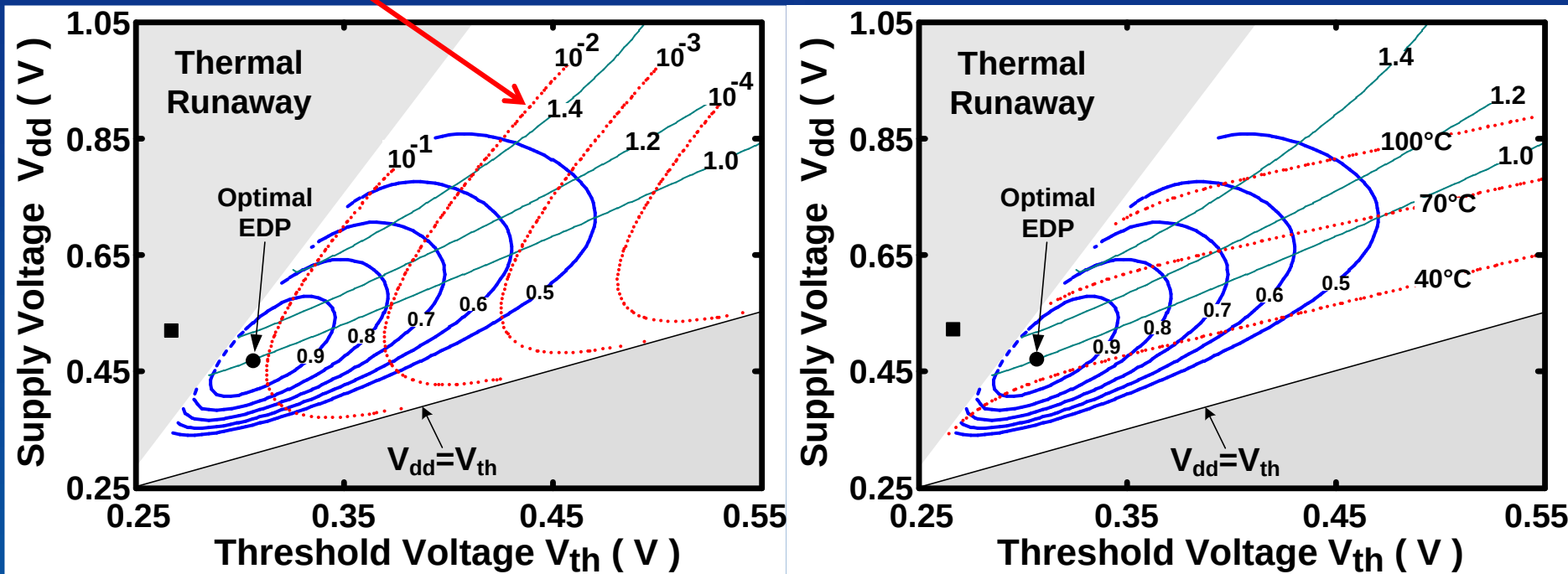
$$Energy = (P_{dynamic} + P_{static}) \cdot T_g L_d$$



EDP contours: 0.5 implies  $EDP = 2 \text{ EDP}_{opt}$

# Electrothermally-Coupled EDP

Iso-leakage curves: leakage-power/total-power



Lin et al., TVLSI 2008

- ❖ A shift in optimal point, EDP and performance contours
- ❖ An overall change in shape of EDP contours
- ❖ Iso-temperature curves generated using self-consistent methodology—provide additional thermal (or reliability) constraint
- ❖ Operation region restricted by electrothermal constraints



# Generalized Metric for Optimization

❖ EDP is not the only metric

❖ Other Metrics.....

**EDP is Energy X Delay =  $PT^2$**

**PDP is Power X Delay =  $PT$**

**PEP is Power X Energy =  $P^2T$**



**Generalized Metric:  $PT^\mu$**

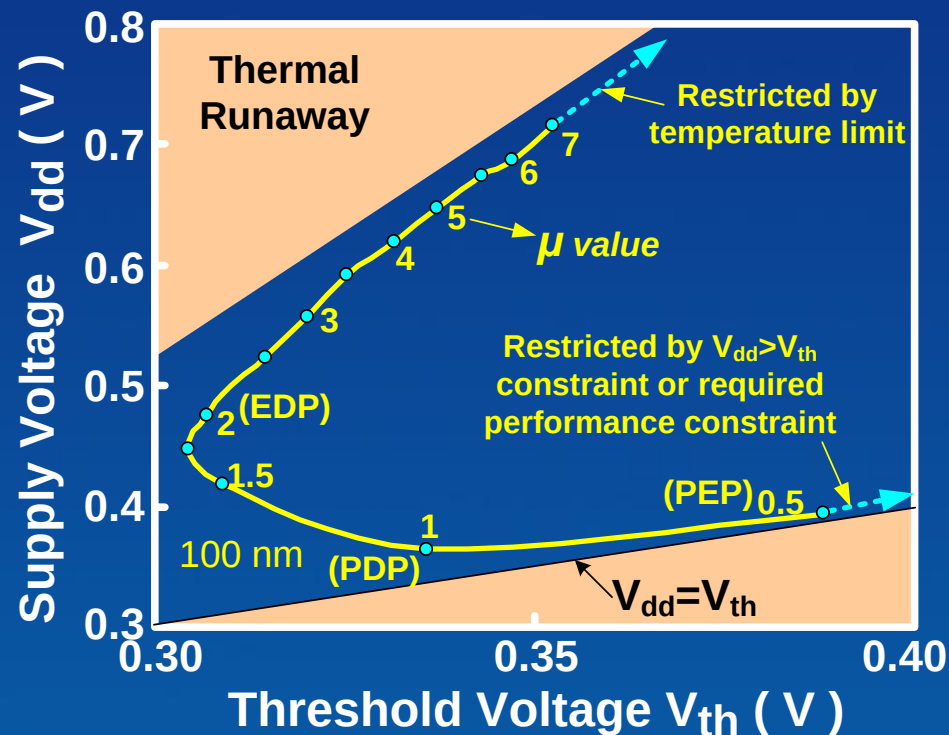
$\mu$  is the ratio of the exponent of delay over that of power ( $\mu = 2$  for EDP)

**How to choose a design-specific metric ?**

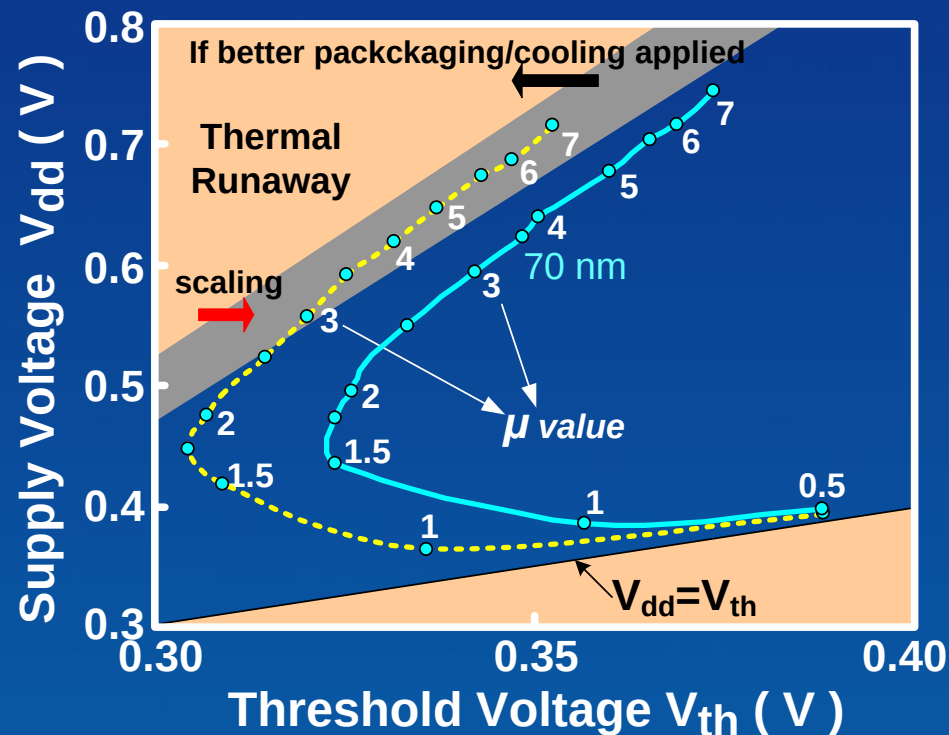


# Optimal Operation Locus

Optimal operation locus for 100 nm node



Effect of scaling on optimal operation locus

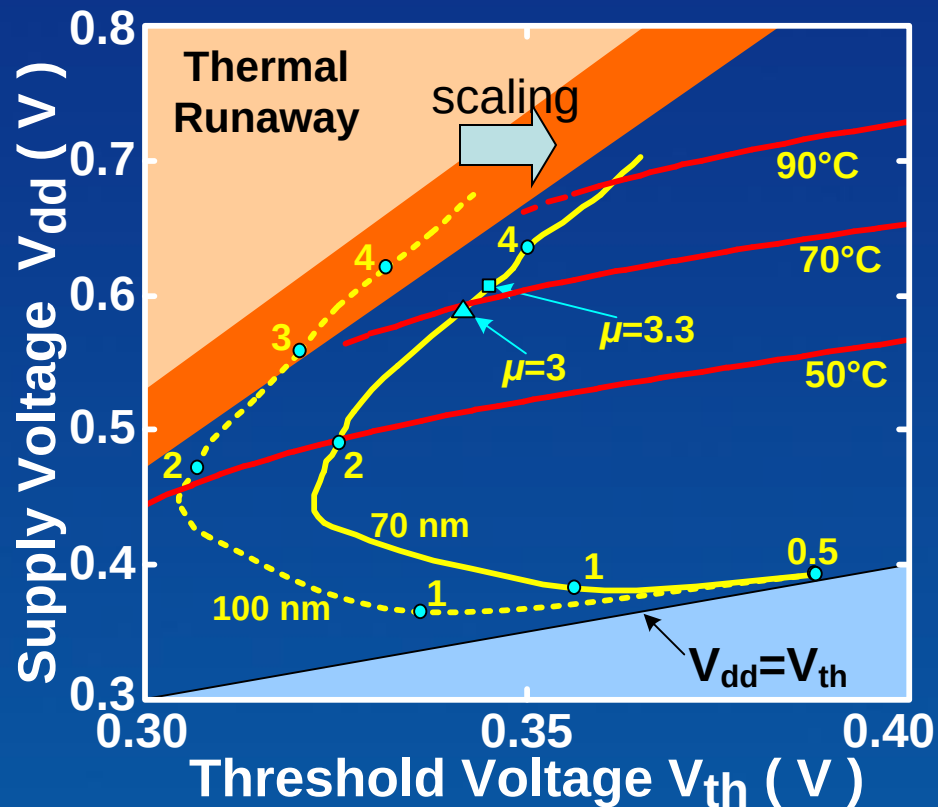
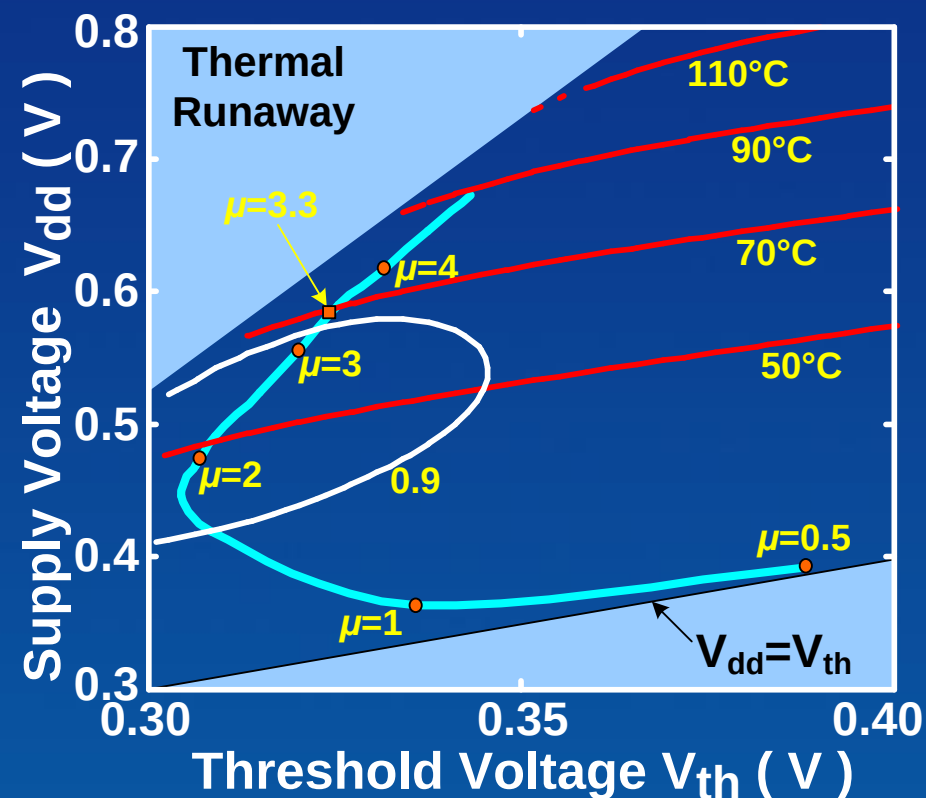


$\mu$  is determined by thermal and performance requirements





# Thermal/Packaging Aware Design Optimization



- ❖ Choose an optimization metric to meet thermal/packaging requirements (For  $T = 70^\circ\text{C}$ ,  $\mu = 3.3$ )
- ❖ Impact of scaling should be taken into account (For  $T = 70^\circ\text{C}$ ,  $\mu = 3$ )



# IC Cooling for Power/Thermal Management?

S-C. Lin and K. Banerjee, "Cool Chips: Opportunities and Implications for Power and Thermal Management," TED Vol. 55, No. 1, pp. 245-255, Jan 2008.

## Efforts on Low-Power.....without hurting performance ...

### ❖ Device Engineering

- ❖ Enhanced Channel Mobility – Strained Silicon
- ❖ Reduced Gate Leakage – High-K Gate
- ❖ Reduced Junction Leakage – Nitrogen Doped

### ❖ Circuit Level

- ❖ Adaptive body-biasing, Dual  $V_{DD}$ -CMOS, Dual- $V_{th}$
- ❖ Sleep Transistor, Clock/Power Gating

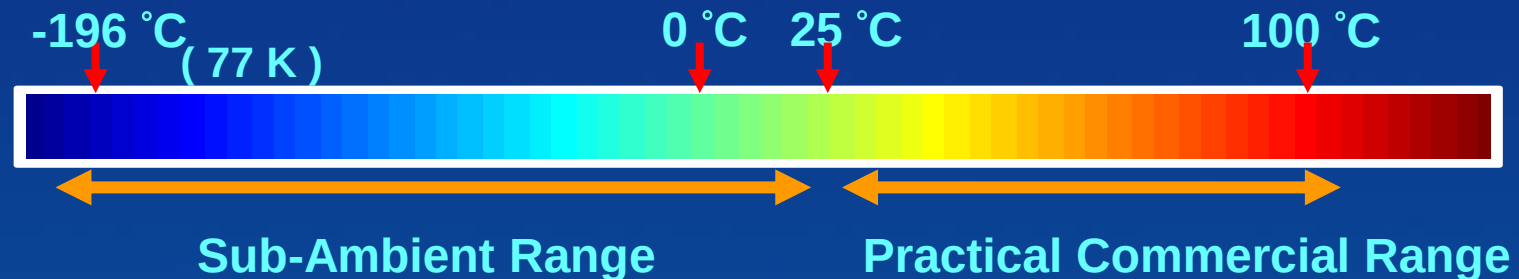
### ❖ Micro-Architecture Level

- ❖ Multi-Core



# Does IC Cooling Make Sense?

## ❖ Range of IC Cooling



## ❖ Prior Research on Cooling

### ❖ Analysis under Cryogenic Condition

- Operating near liquid nitrogen temperature ( 77 K ) requires complex cooling facilities
- NOT for commercial purpose

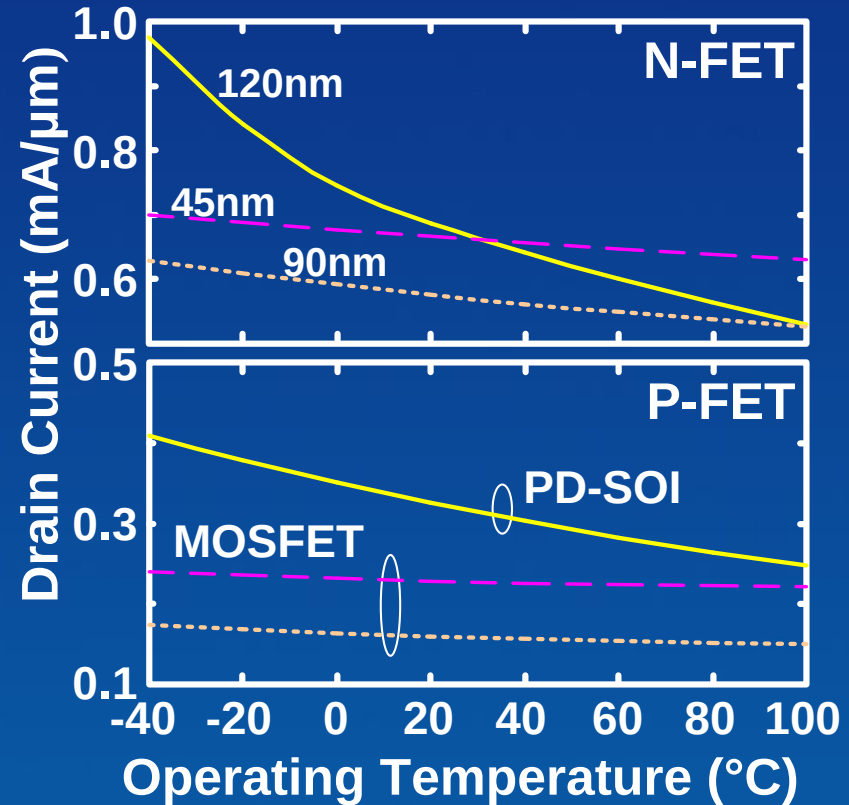
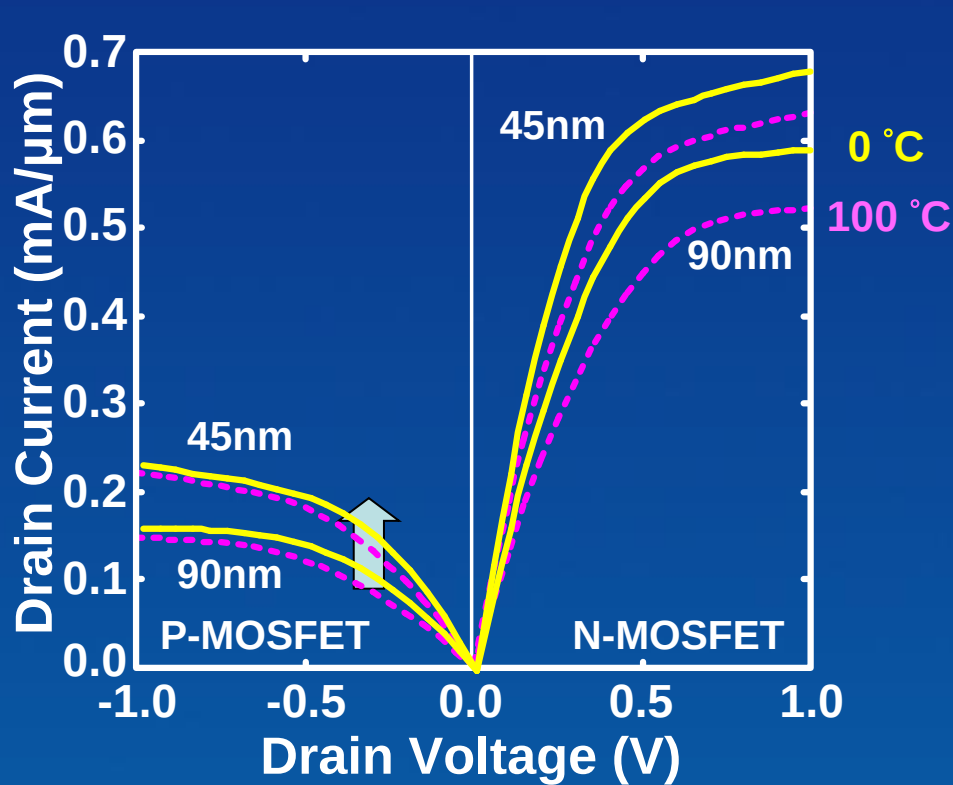
### ❖ Analysis of Performance under Cooling

- Does NOT consider electrothermal couplings
- Does NOT consider the system level power dissipation



# Cooling---Benefit at the Device Level

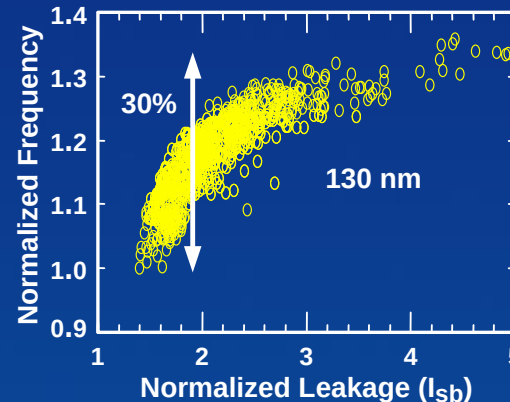
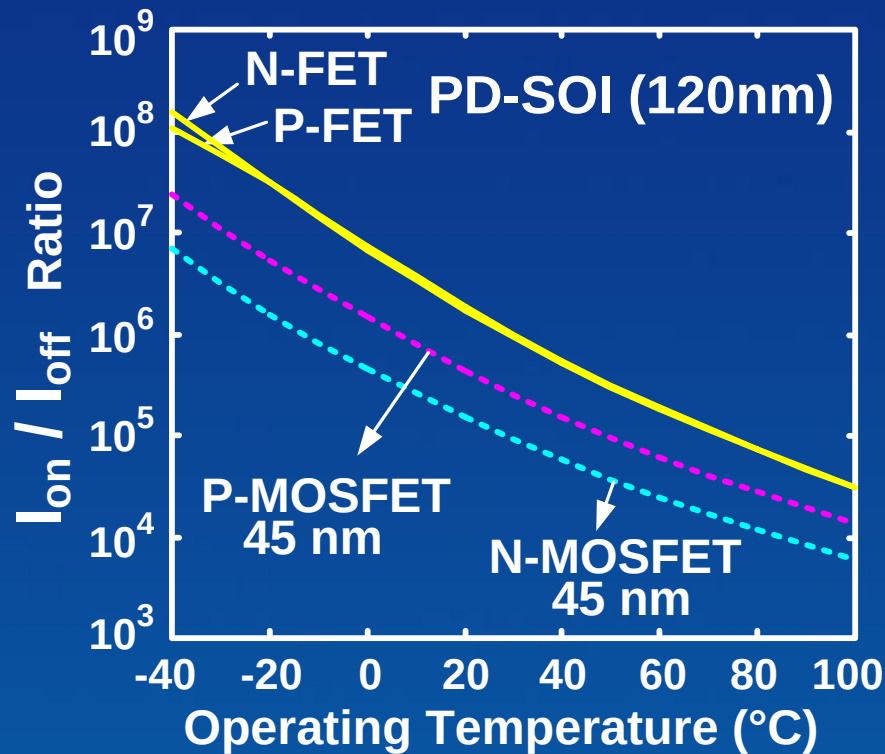
## Transistor Drive Current Increases



Higher drive current can be achieved by cooled operation across all technology nodes due to higher carrier mobility

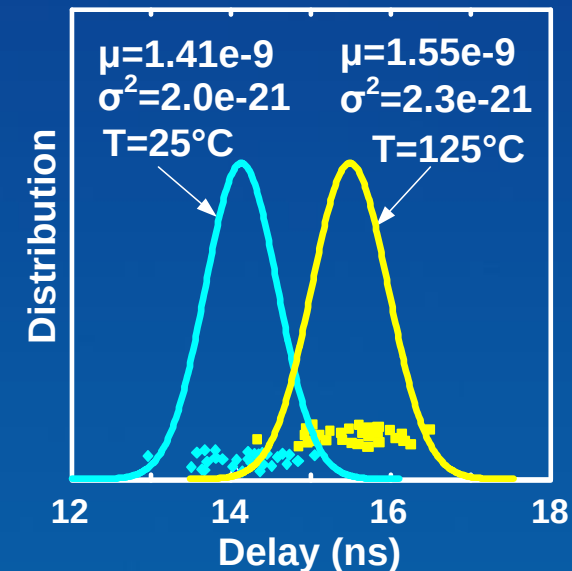


# Cooling---Benefit at the Circuit Level



S. Borkar, Intel

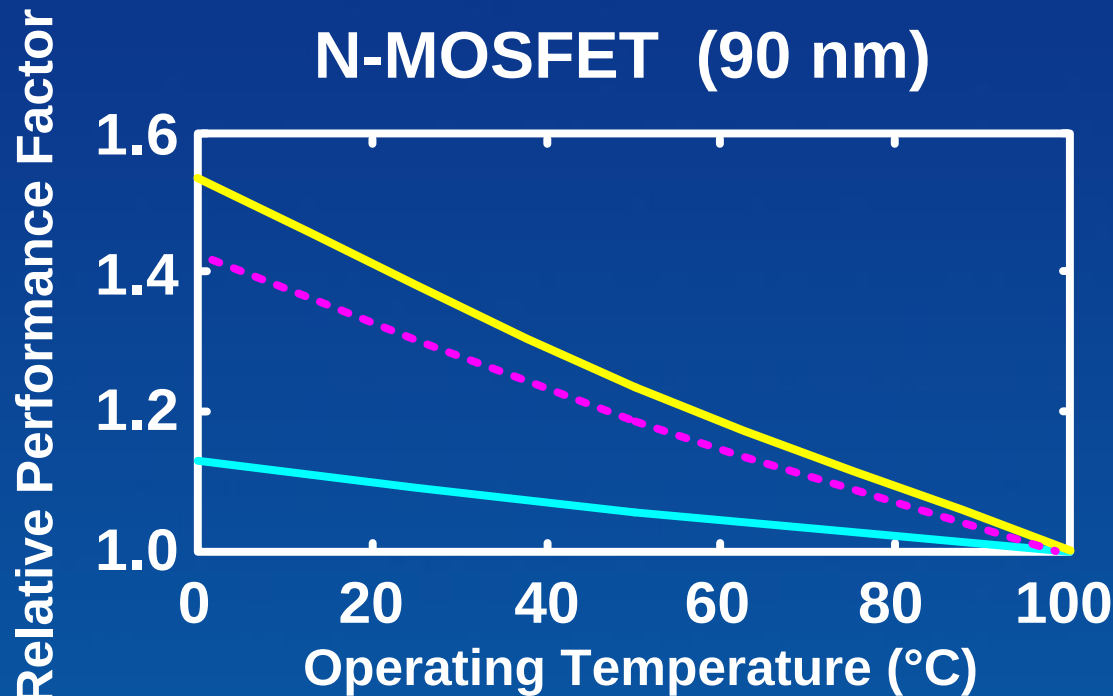
## 9-stage Inverter Chain



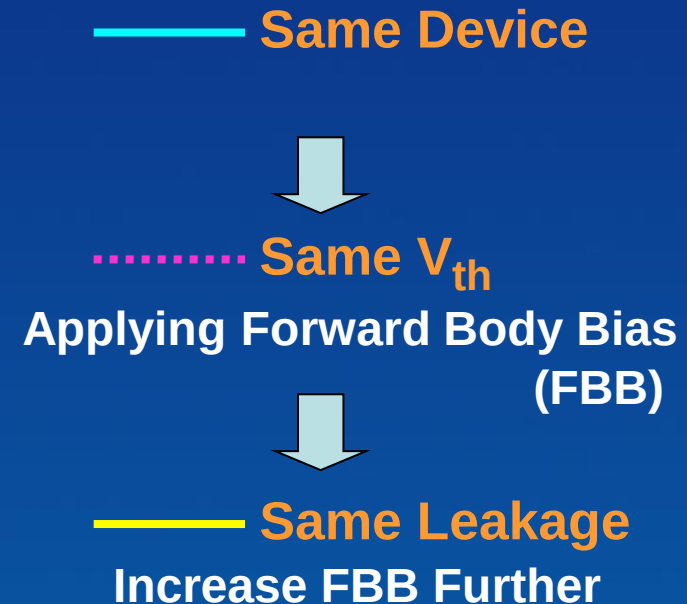
- ❖ Enhance  $I_{on}$  to  $I_{off}$  ratio
- ❖ Reduce propagation delay and variance
- ❖ Benefit back-end performance and reliability



# Further Exploiting the Benefit of Cooling



I. Aller et al., ISSCC 2000

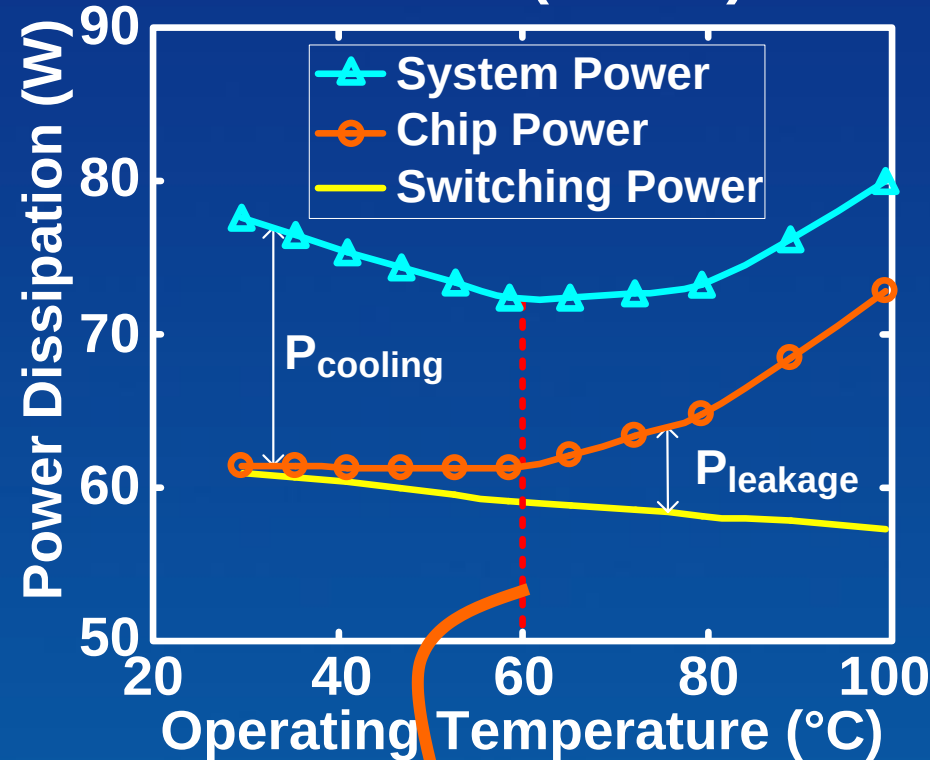


Performance can be further improved by different design strategies

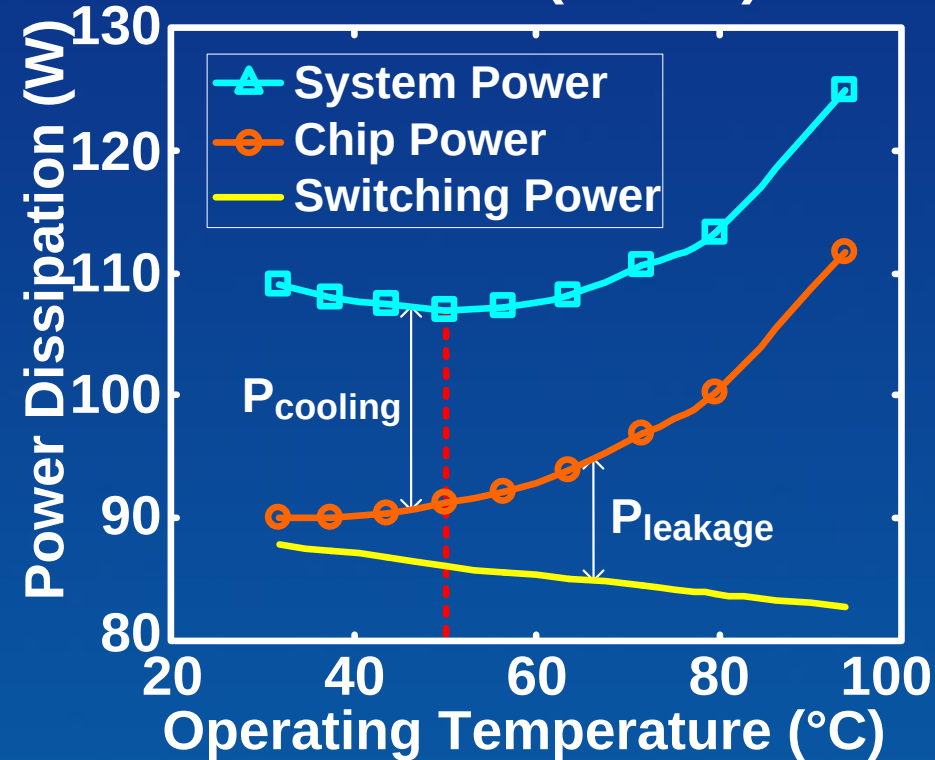


# Cooling---System Level Considerations

Module (90 nm)



Module (45 nm)

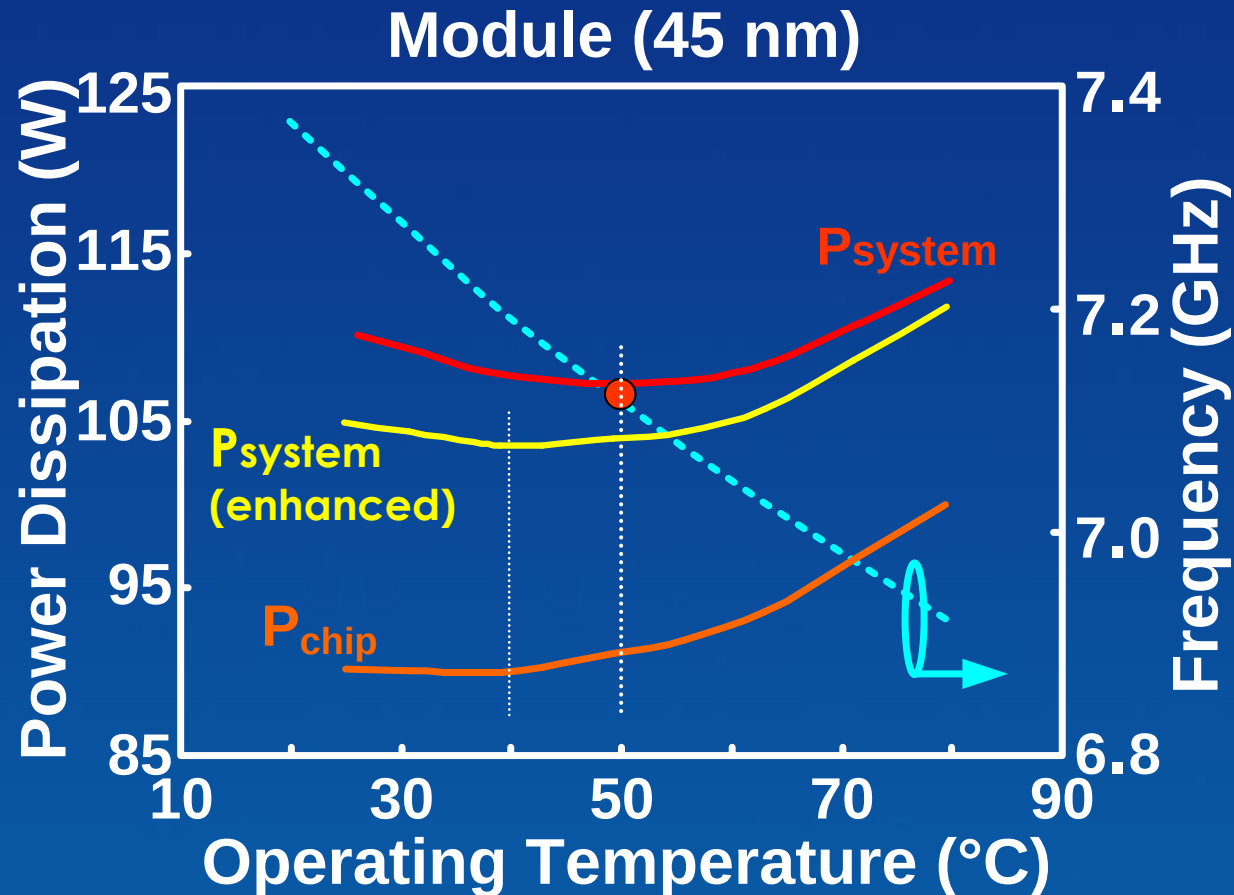


Beyond this point, further cooling does not lead to any power saving.

The limit occurs at a lower temperature as technology scales.



# Extending the Practical Limit of Cooling

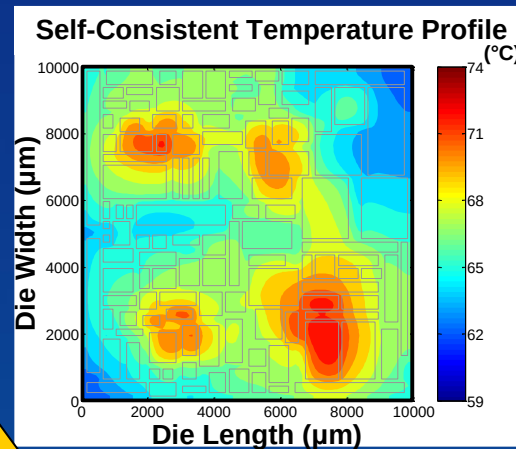
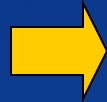
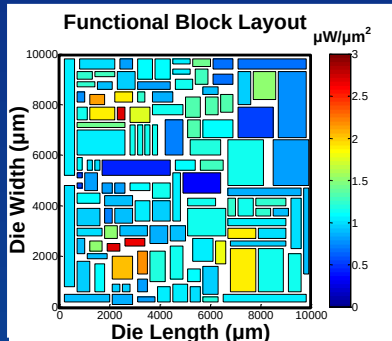


Practical limit can be further extended towards a lower temperature and higher performance is achieved by enhancing cooling efficiency

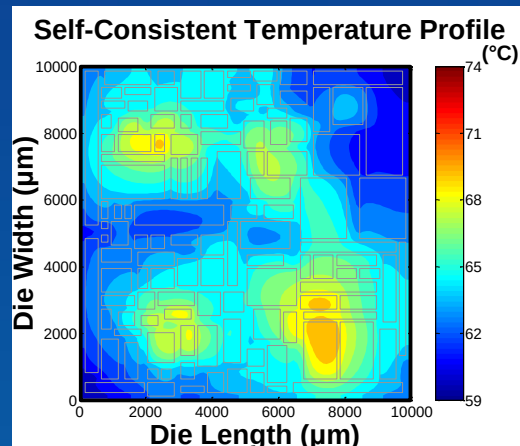




# Hot-Spot Management

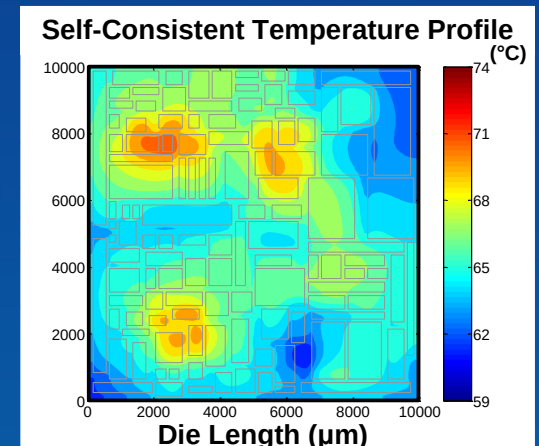


$T_{\text{MAX}}$  decreases  
but hot-spots remain



Global Cooling

Thermal resistance reduces 20%



Localized Cooling

Localized cooling will be more effective for hot-spot management



# Conclusion

---

- ❖ For power/thermal management of nanoscale CMOS ICs, **electrothermal couplings** must be incorporated for trading-off chip-level power, performance, reliability, and cooling cost.
- ❖ An accurate leakage-aware **self-consistent power and silicon-substrate temperature-profile-estimation** technique has been developed for nanoscale CMOS technologies.
- ❖ A systematic methodology for power-performance optimization has been developed to **bring design and packaging closer**.
- ❖ **Chip cooling** combining device, circuit, and system level considerations can extend CMOS scaling.



# Additional Issues....

---

- ❖ Extend CMOS scaling
  - ❖ Time per node can be expanded via cooling
- ❖ Application Based
  - ❖ High-performance servers
  - ❖ Hand-held applications
- ❖ Implications for Ultra Low-Voltage Applications
  - ❖ Positive Temperature Dependence

